

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/733,201
Filing Date December 9, 2003
Confirmation No. 5994
Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner Kelly M. Stouffer
Attorney's Docket No. MI22-2402
Customer No. 021567
Title: Atomic Layer Deposition Method of Depositing an Oxide on a Substrate

RESPONSE TO JANUARY 18, 2008 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 West First Avenue, Suite 1300
Spokane, WA 99201-3828

Responsive to the Office Action dated January 18, 2008, Applicant amends
and remarks as follows:

AMENDMENTS